

Abstract

The present invention relates to a device (10) for cleaning
pot-shaped hollow bodies (12), in particular transport
5 containers (30) for semiconductor wafers or for lithography
masks, wherein the hollow body (12) comprises a base wall (32)
and one or more side walls (34) that form an inner hollow body
surface (33) and an opening (36) that is disposed opposite the
base wall (32) and that is surrounded by a marginal surface
10 (38) of the side wall (34). The device (10) comprises a
support wall (20) on which the marginal surface (38) of the
hollow body (12) can be placed, a cleaning device (40) by
which a first cleaning fluid for cleaning the inner hollow
body surface (33) can be dispensed when the hollow body (12)
15 is connected to the support wall (20) and a feed device (37)
that is arranged in the support wall (20) or is fastened to
the support wall (20) and by which a flushing fluid can be
guided to the marginal surface (38), with the feed device (37)
comprising a movable element (39) that is movable toward the
20 marginal surface (38) by the flushing fluid.

(Figure 1B)